



## MAGNETO-ELECTRIC BASED MAGNETIC SENSOR AND METHOD THEREOF

### IITM Technology Available for Licensing

#### Problem Statement

- Existing magnetic sensors are layered structures using epoxy bonding are limited in their ability to **sense magnetic fields only within their own plane**, and **epoxy properties degrade significantly at temperatures beyond 50°C**.

The present patent application aims to address these limitations by developing a **reliable and efficient magnetic sensor** that eliminates the issues associated with the traditional magnetostrictive materials.

#### Technology Category/ Market

**Categories:** Applied Mechanics & Mechanical Engineering | Electronics & Circuits

**Technologies:** Magnetolectric (ME) & Sensor Technology, Transportation, Security, Industrial Manufacturing, Automation, R&D, Energy & Power Aerospace & Defense, Environmental Monitoring.

**Application:** providing epoxy-free magnetic sensors for elevated temperature detection, enabling multi-directional magnetic field sensing, enhancing output voltage, eliminating epoxy bonding, and extending the sensing range.

**Market:** The global magnetic sensor market was valued at **USD 4.43 billion in 2021** and is expected to reach **USD 8.02 Billion by 2030**, growing at **7.5% CAGR from 2022 – 2030**.

#### Technology

The present patent discloses **magneto-electric based magnetic sensor**. This technology is a **press-fit magnetic sensor** with a multi-directional detection capability, designed for reliable operation at **elevated temperatures**.

It eliminates the use of **epoxy bonding**, **ensuring high-temperature stability**, and offers customization options for industrial use.

The present patent discloses **methods of:**

- Fabrication of Press-Fit Magnetic Sensor**
- Detection of Magnetic Fields.**

#### Research Lab

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Department of Applied Mechanics

#### Key Features / Value Proposition

##### ❖ User Perspective:

- Reliable in High Temperatures:** Users benefit from the sensor's high-temperature reliability.
- Versatile multi-directional magnetic field detection suits various applications.
- Extended Range:** The extended sensing range is valuable for distant magnetic field detection.

##### ❖ Technology Perspective:

- Epoxy-Free Design:** Epoxy-free design simplifies manufacturing and enhances longevity.
- Press-fit technology improves sensor robustness.
- Customizable Dimensions:** Option of Flexible customization to adapt with various industry needs.

##### ❖ Industrial Perspective:

- Improved Automation:** Enhanced reliability aids manufacturing and automation.
- Cost Efficiency**
- Industries benefit from extended usability in elevated temperatures and longer distances.

#### Intellectual Property

**IITM IDF Number: 2257**  
**IN Patent number: 411667 (granted)**

#### TRL (Technology Readiness Level)

**TRL – 3; Proof of Concept**

#### Images



**FIG. 1** depicts an ME based press-fit magnetic sensor, in accordance with an embodiment;



**FIG. 2** depicts an exemplary conventional layered magnetic sensor

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#### Methods Disclosed in the Invention

##### ❖ Fabrication of Press-Fit Magnetic Sensor:

1. **Sensor Structure Creation:** Form a sensor structure with multiple faces using a magnetostrictive material, which can be shaped into various forms like cuboids or prisms.
2. **Slot Machining:** Machine at least one slot in each face of the sensor structure to accommodate piezoelectric discs.
3. **Piezoelectric Disc Fitting:** Fit at least one piezoelectric disc into each slot of the sensor structure to enable the detection of magnetic fields from different directions.
4. **Optional Auxiliary Top Plate:** Fabricate an auxiliary top plate from the same magnetostrictive material and attach it to the sensor structure to create an additional face for enhanced sensor performance.
5. **Additionally, measure the direction and angle of the magnetic field by separately analyzing the output voltage generated by each piezoelectric disc (Soldering Wires: Solder wires to the positive and negative electrodes of the piezoelectric disc to facilitate the extraction of voltages generated during magnetic field detection.)**

##### ❖ Detection of Magnetic Fields:

1. **Sensor Placement:** Place the press-fit magnetic sensor (100) in a location with at least one magnetic field source to be detected.
2. **Voltage Generation:** As the sensor detects magnetic fields, one or more voltages are generated by the piezoelectric discs (108) within the sensor.
3. **Signal Transmission:** Transmit the generated output voltages as signals through the soldered wires to an external system for further analysis.
4. **Analysis and Measurement:** Analyze the generated output voltages to detect the presence of at least one magnetic field.
5. **Additionally, measure the direction and angle of the magnetic field by separately analyzing the output voltage generated by each piezoelectric disc (108).**

FIG. 3 depicts an experimental setup for testing the ME based press-fit 30 magnetic sensor

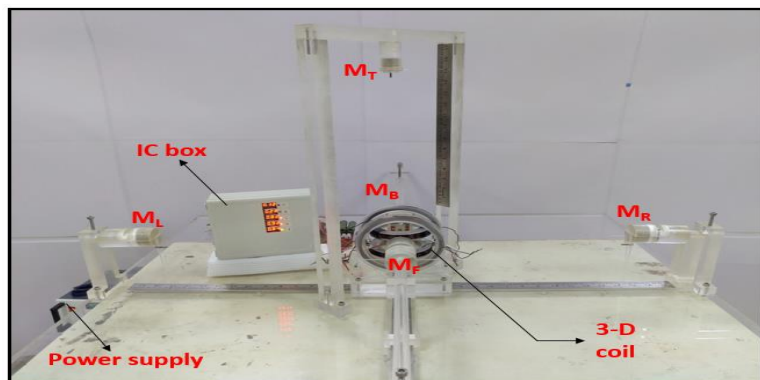
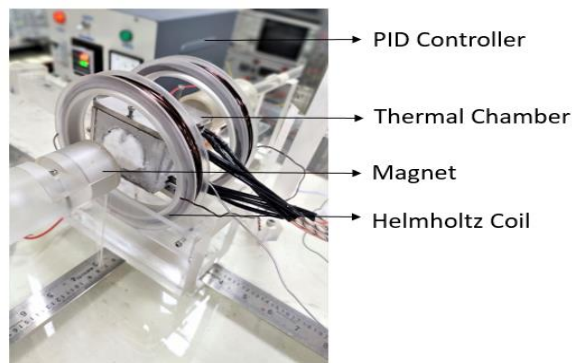


FIG. 4 shows an experimental setup for testing the proposed thermally stable press-fit magnetic sensor



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